Supporting information for

Optimization of ammonium fluoride route to hierarchical zeolites

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Figure S2: ²⁷Al MAS NMR spectra of the parent NH₄-ZSM-5 and of samples etched in 20 g of a 40 wt% NH₄F solution for 0.5; 1.0; 1.5 and 2.0 h. Amount of zeolite used: 1 g (a), 2 g (b) and 4 g (c).

Figure S3: N_2 adsorption isotherms (a, c, e) and BJH pore size distribution (b, d, f) of the parent NH₄-ZSM-5 and the samples etched in 20 g of a 40 wt% NH₄F solution for 0.5; 1.0 and 2.0 h. Amount of zeolite used: 1 g (a, b), 2 g (c, d) and 4 g (e, f).

Figure S4: (a) XRD patterns and (b) 27 Al NMR spectra of the parent NH₄-ZSM-5 and the samples etched for 2.0 h in a solution containing 1.0; 0.5 or 0.25 g of NH4F and 12 g of water. Amount of zeolite used: 1 g.

Figure S5: (a) N_2 adsorption isotherms and (b) BJH pore size distributions of the parent NH₄-ZSM-5 and the samples etched in a solution containing from 1 to 0.25 g of NH₄F and 12 g of water. Amount of zeolite is 1 g. Note: (a) Isotherms have been offset for the sake of clarity.

Figure S6: TEM monitoring of the dissolution of MFI as a function of the concentration of NH₄F (wt%) etching solution for 2h treatment: (a) NH₄F(6)-ZSM-5(1)-2; (b) NH₄F(4)-ZSM-5(1)-2; (c) NH₄F(2)-ZSM-5(1)-2; (d) NH₄F(1)-ZSM-5(1)-2.

Table S1: Initial F/(Al+Si) atomic ratio of the NH₄F/ZSM-5/water suspension, maximum yield of the etching and Si/Al atomic ratio and porosity of parent and NH₄F treated ZSM-5.

Sample codes: In the following, the samples will be denote: $NH_4F(X)$ -ZSM-5(Y)-Z where X and Y respectively stand for the weight of NH_4F and NH_4 -ZSM-5 in gram per 12 g of water and Z correspond to the reaction duration in hour.



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Samples	F/(Al+Si) _{ini} a	$% Y_{max}$	Si/Al ^b	S_{BET} m ² g ⁻¹	$\frac{S_{Ext}^{c}}{m^{2} g^{-1}}$	V_{micro}^{c} cm ³ g ⁻¹	V_{meso}^{d} cm ³ g ⁻¹
NH ₄ -ZSM-5	-	-	17	325	14	0.16	0.03
NH ₄ F(8)-ZSM-5(1)-0.5		-	16	345	35	0.15	0.19
NH ₄ F(8)-ZSM-5(1)-1	12.4	-	18	332	37	0.15	0.25
NH ₄ F(8)-ZSM-5(1)-2		10	13	299	40	0.14	0.23
NH ₄ F(8)-ZSM-5(2)-0.5		-	18	342	37	0.16	0.13
NH4F(8)-ZSM-5(2)-1	6.2	-	18	345	35	0.16	0.22
NH4F(8)-ZSM-5(2)-2		25	15	355	37	0.15	0.28
NH ₄ F(8)-ZSM-5(4)-0.5		-	14	340	40	0.15	0.10
NH ₄ F(8)-ZSM-5(4)-1	3.1	-	14	336	37	0.16	0.15
NH ₄ F(8)-ZSM-5(4)-2		60	14	360	31	0.16	0.18

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